

## ➔ NC-10 Non-contact sheet resistance/resistivity measurement instrument with PC



### Selling Points

- Easy operation and data processing by PC
- No damage measurement by non-contact eddy current method
- Replaceable probes by meas. range (\*Second or more probe is for the option)
- 1 point measurement of center position, 5 types of model for each measuring range
- Temperature correction for silicon wafer function

### Details

#### Applications

- Semiconductor materials, Solar-cell materials (Silicon, Polysilicon, SiC etc)
- New materials, functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Silicon-related epitaxial materials, Ion-implantation sample
- Chemical compound semiconductor (GaAs Epi, GaN Epi, InP, Ga etc)
- Others (\*Please contact us for details)

#### Sample sizes

3 ~ 8 inch, ~156x156mm (Option; 2 inch and/or 12 inch, ~210x210mm)

#### Measuring range

[R] 1m ~ 200  $\Omega \cdot \text{cm}$  [RS] 10m ~ 3,000  $\Omega/\text{sq}$

\* The range is separated from each Low, Middle, High and S-High probe type.

\*Please refer the measurement range for each probe type as below;

- |  |  |
|--|--|
| ① Low : 0.01~0.5 $\Omega/\text{sq}$ (0.001~0.05 $\Omega \cdot \text{cm}$ ) | ③ High : 10~1000 $\Omega/\text{sq}$ (0.5~60 $\Omega \cdot \text{cm}$ )     |
| ② Middle : 0.5~10 $\Omega/\text{sq}$ (0.05~0.5 $\Omega \cdot \text{cm}$ )  | ④ S-High : 1000~3000 $\Omega/\text{sq}$ (60~200 $\Omega \cdot \text{cm}$ ) |

